

EXHIBIT H

Ocean Semiconductor notes that the present claim chart and analysis are necessarily preliminary in that Ocean S obtained substantial discovery from Huawei nor has Huawei disclosed any detailed analysis for its non-infringement pos Semiconductor does not have the benefit of claim construction or expert discovery. Ocean Semiconductor reserves the r amend the positions taken in this preliminary and exemplary infringement analysis, including with respect to literal infri under the doctrine of equivalents, if and when warranted by further information obtained by Ocean Semiconductor, inclu information adduced through information exchanges between the parties, fact discovery, claim construction, expert disc

USP No. 6,660,651	Infringement by the '651 Accused Instrumentalities
<p>19. A method, comprising: providing a process chamber comprised of a wafer stage, said wafer stage having a surface that is adjustable;</p>	<p>ASML's TWINSCAN system provides a process chamber comprised of a wafer stage, t surface that is adjustable.</p> <p>For example, the TWINSCAN system performs the method of providing a process chan</p>  <p>The image shows an ASML TWINSCAN NXT:1980Di lithography system. It is a large, industrial-grade machine with a white and blue color scheme. The front panel features the ASML logo and the model name 'TWINSCAN NXT:1980Di'. The machine is open, revealing a complex internal structure with various components, including a wafer stage and a lens system. The machine is mounted on a dark blue base.</p> <p>See ASML DUV Lithography Systems, available at https://www.asml.com/en/products/systems/twinscan-nxt1980di (last visited Apr. 30 2019).</p> <p>The process chamber can be used for wafer exposure during lithography:</p>

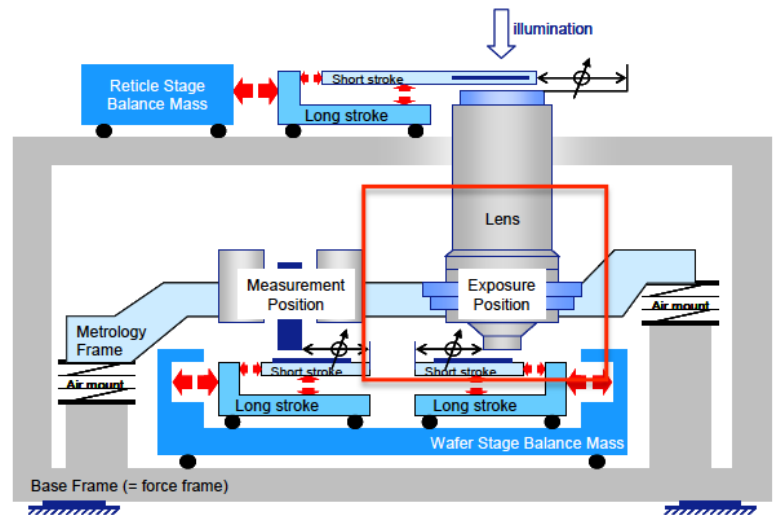


Figure 5. TWINSCAN™ dynamic architecture

See Perspective on Stage Dynamics and Control at 3.

The process chamber includes an adjustable wafer stage having a surface that is adjustable.

“In Figure 4, the table holding the wafer is called the mirror block because of the mirrors that allow interferometric position measurement (IFM).”

See Position Control at 31.

For example, the adjustable wafer stage or mirror block of the TWINSCAN system is sl

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